

MAY 05 2003

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Inventor : Manfred ROTHLEY et al.  
 Serial No. : 09/720,938  
 Filing Date : May 2, 2001  
 For : APPARATUS FOR SENSING ELECTROMAGNETIC RADIATION  
 Group Art Unit : 2878  
 Examiner : C. Hannaher

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I hereby certify that this correspondence is being deposited with the United States Postal Service as first class mail in an envelope addressed to: Commissioner for Patents, Washington, D.C. 20231 on

30 April 2003

Michelle M. Camiaux (Reg. No. 36,098)

Commissioner for Patents  
 Washington, D.C. 20231

TRANSMITTAL

SIR:

Please find an Amendment transmitted herewith for filing in the above-identified patent application.

Applicants hereby request a two-month extension of time for responding to the Office Action of December 24, 2002. The extended period for response expires on May 24, 2003. Please charge the \$410.00 extension fee and any other fee that may be required to Deposit Account No. 11-0600. A duplicate of this Transmittal is enclosed.

Respectfully submitted,

KENYON & KENYON

(Reg. No. 36098)

Dated: 30 April 2003

By:

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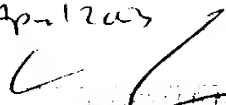
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30 Apr 12 2003



CLINTON A. KENYON

**AMENDMENT**

Dear Sir:

This amendment addresses the Office Action mailed December 24, 2002. Please enter the following amendment in the above-captioned application.

**In the Claims:**

Please cancel claim 20, without prejudice.

Please amend the claims as set forth below.

19. (Amended) An apparatus for sensing electromagnetic radiation, comprising:

a detector structure to sense electromagnetic radiation, the detector structure formed on a semiconductor substrate;

a protective window for the detector structure, and

a micromechanical optical imaging system including a lens configured to form an image of a subject to be imaged onto a plane of the detector structure, the lens having a convexity on a side facing away from the detector structure, the lens being arranged relative to the detector structure so that a cavity is between the lens and the detector structure.